

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination NAKAZAWA ET AL.	
		10/822,820	Examiner	Art Unit
		Granvill D. Lee, Jr	2891	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,241,817	06-2001	Jang et al.	117/8
	B	US-6,013,544	01-2000	Makita et al.	438/166
	C	US-5,994,164	11-1999	Fonash et al.	438/97
	D	US-5,916,717	06-1999	Yang et al.	430/30
	E	US-5,654,203	08-1997	Ohtani et al.	438/97
	F	US-5,700,333	12-1997	Yamazaki et al.	136/258
	G	US-6,809,023	10-2004	Arai et al.	438/623
	H	US-6,734,050	05-2004	Nakazawa et al.	438/151
	I	US-6,465,287	10-2002	Yamazaki et al.	438/162
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages
	U	Kitano T. "Novel coating apparatus using nozzle-scan technique" Semiconductor manufacturing, 2000. Proceedings of ISSM 2000. The ninthe intern. Symposium on, 26-28 Sept. 2000, pg. 395-398.
	V	Ito et al. "The performances of the novel nozzle-scan coating method" Micropocesses and nanotechnology conference, 2000 internation 11-13 July 2000, pg. 298-299.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.